



DOCKET NO: 240882US0

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF

TOMOHISA KONNO, ET AL.

: EXAMINER: RACHUBA, MAURINA T.

SERIAL NO: 10/626,521

:

FILED: JULY 25, 2003

: GROUP ART UNIT: 3723

FOR: AQUEOUS DISPERSION FOR  
CHEMICAL MECHANICAL POLISHING  
AND PRODUCTION PROCESS OF  
SEMICONDUCTOR DEVICE

AMENDMENT AND REQUEST FOR RECONSIDERATION UNDER 37 CFR 1.114

COMMISSIONER FOR PATENTS  
ALEXANDRIA, VIRGINIA 22313

SIR:

In response to the Office Action dated July 7, 2006, Applicants respectfully request reconsideration of the above-identified application in view of the following amendments and remarks:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Support for the Amendment** begins on page 7 of this paper.

**Request for Reconsideration** begins on page 8 of this paper.